

Not Just Chips

April 4-6, 2023



www.meptec.org



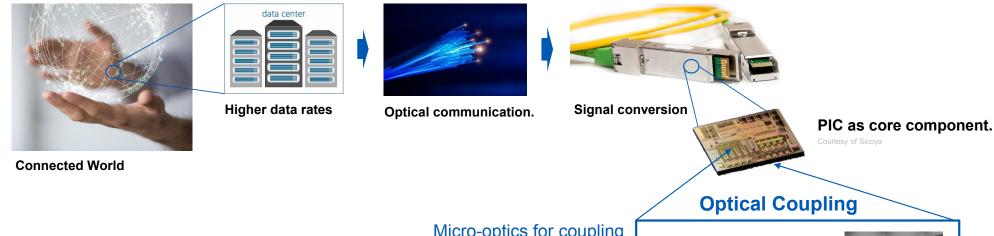
UFO Probe® Card: Enabling high volume data communication – solving the new challenges in PIC wafer testing.



Enabling high volume data communication...

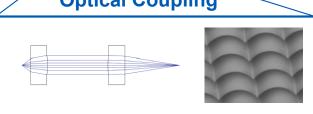
What can Jenoptik do?

It is all about optical communication...



Micro-optics for coupling

- Fiber-to-PIC
- Laser-to-PIC
- Fiber-to-Fiber





Enabling high volume data communication...

What can Jenoptik do?

It is all about optical communication...

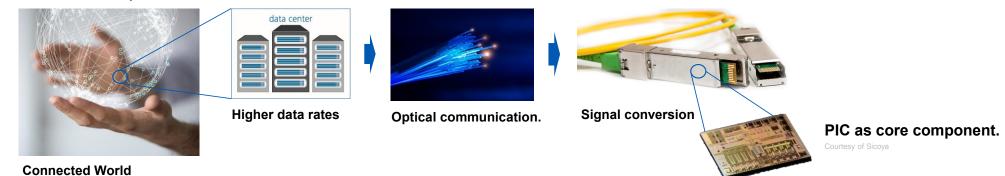




Enabling high volume data communication...

What can Jenoptik do?

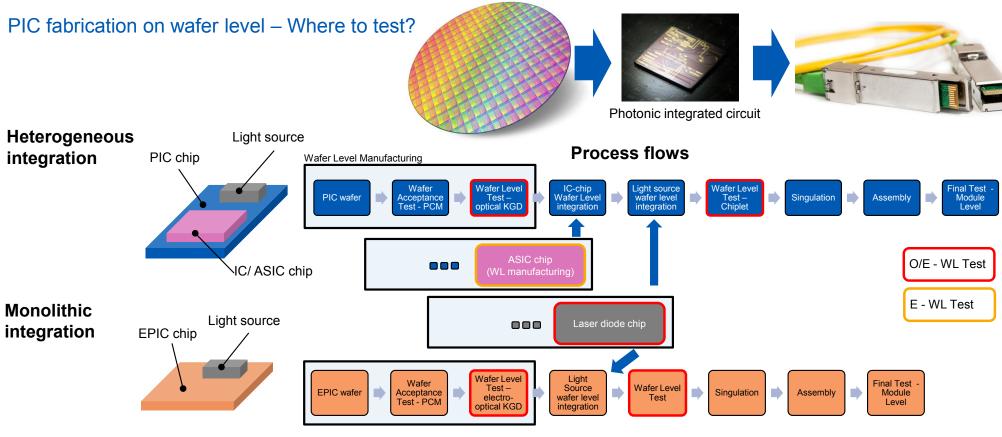
It is all about optical communication...



Optical Wafer-level Testing







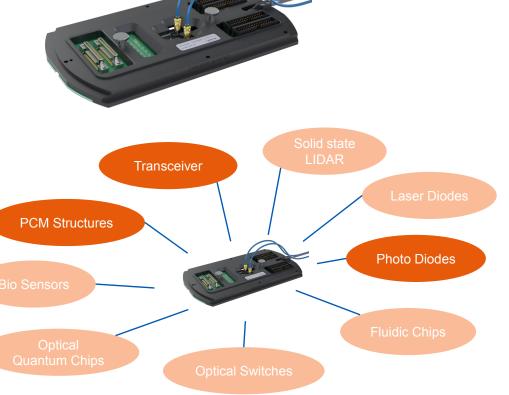


UFO Probe® - <u>u</u>ltra-<u>f</u>ast <u>o</u>pto-electronic probe card.

JENOPTIK's solution for high-volume wafer level test of photonic integrated circuits (PIC).

Current PIC Test Applications in focus

- Optical Transceivers ramping up
- Monitoring PIC manufacturing process (PCM)



UFO Probe® Card – Jenoptik's solution for PIC WLT

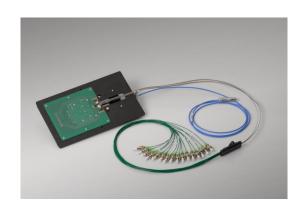


USP

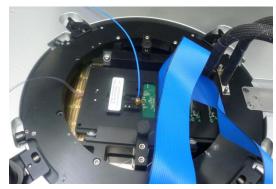
- Plug & Play' ready for existing standard IC wafer probers and automated test equipment
- No active alignment time per chip
- Parallel qualification possible → multi-DUT regime
- Operated by same personnel as standard IC equipment

Benefits

- optical and electrical probe integrated in a single probe card
- Compatible to existing interfaces
- Optics that works alignment insensitive and
- Deals with ,coarse' prober alignment tolerances
- Scalable solution with simple handling







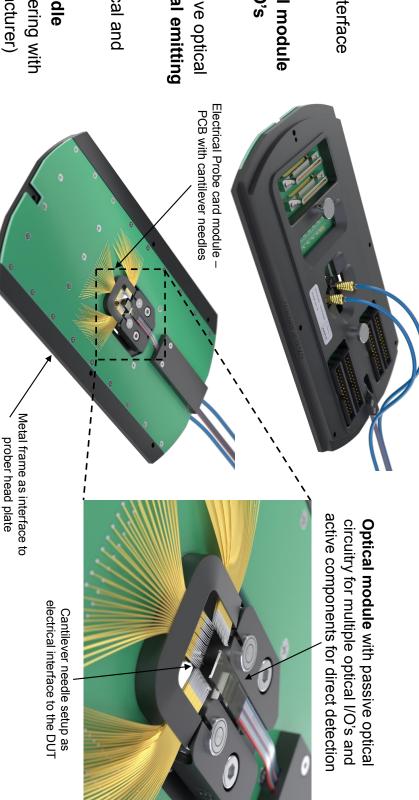
Courtesy of Rood Microte

UFO Probe® Card – Key Figures



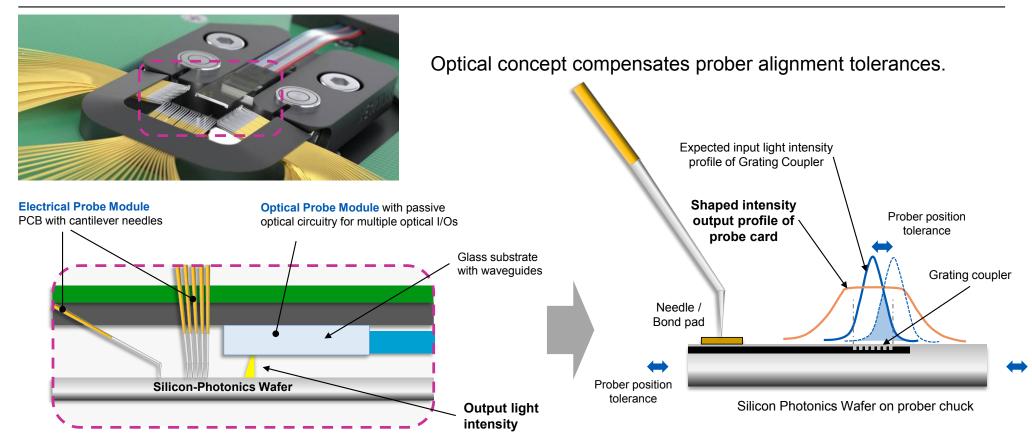
Key figures

- Standard prober interface (Eurocard format)
- Monolithic optical module with 16 optical I/O's (up to 32ch)
- Alignment insensitive optical coupling for vertical emitting
 PICs
- Simultaneous optical and electrical probing
- Utilize proven needle technology (partnering with probe card manufacturer)







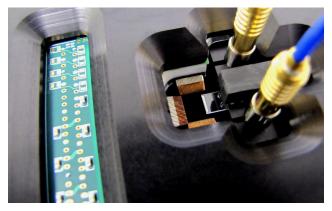


UFO Probe® Card – Integration in existing IC infrastructure



UFO probe card in Eurocard format





Detail of electrical and optical contact module

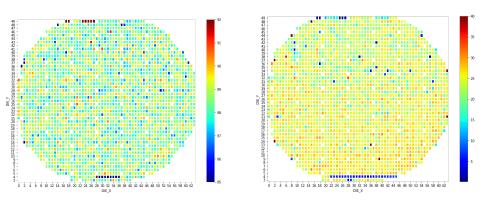


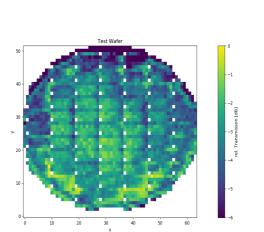
UFO Probe® Card – Wafer-level Test of Customer Device



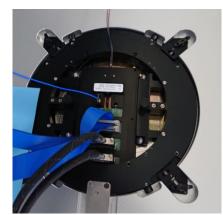
Wafer-level test of transceiver device

- Running as final production test in a customer setup
- RX, TX, alignment channel and comprehensive electrical tests in a single touch-down
- 1x alignment per batch, no additional alignment per chip
- Example of wafer map for Contact Resistance, Receiver supply current and optical alignment channel







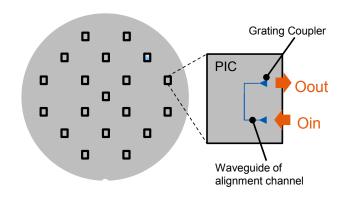


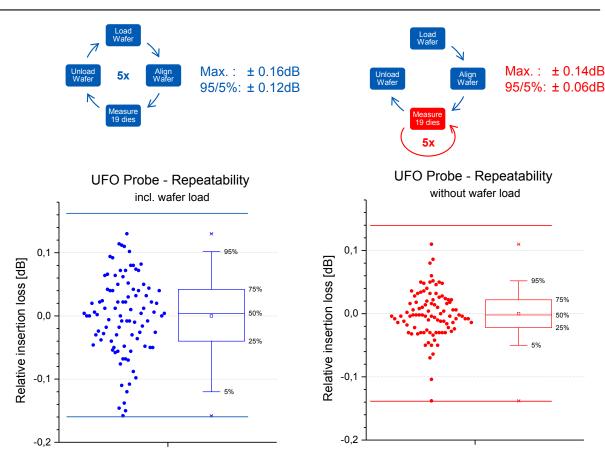




Verification of test capabilities under realistic conditions:

- Measurement of insertion loss of an optical alignment channel
- 19 different chips, spread over the complete wafer
- 5 repetitions of each measurement with and without wafer load





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UFO Probe® Card – Full characterization of Optical Module



All optical channels

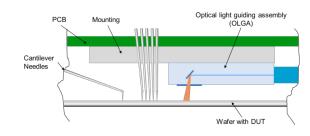
- Beam profile in different
- Beam X,Y position and angle
- Divergence
- Wavelength dependency
- Polarization dependency
- Insertion Loss

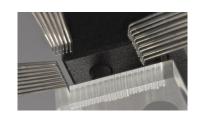
Electrical needles

- Position
- Relative position to optical channels
- Tip quality
- Electrical contact

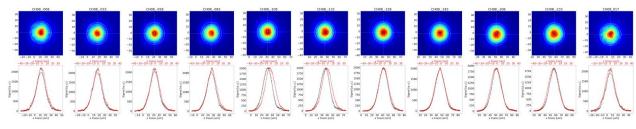
PIC qualification

 Exit beam profile and parameters of PICs vs. input wavelength, polarization and propagation distance





Beam profiles of Optical Module in Z-scan







Different needle tip profiles

Beam profile

Grating coupler

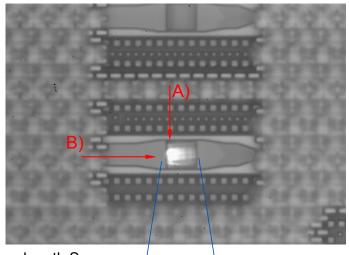
Z

Beam profile of PIC Exit Channel in different Z-heights public





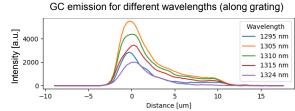
Emission profile of grating couplers at diff. wavelengths



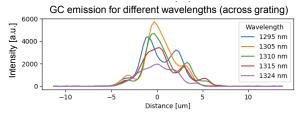
Wavelength Sweep (run presentation to see video)



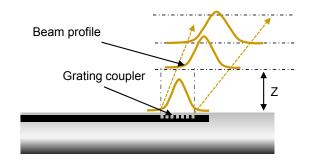
A) Beam profiles across GC

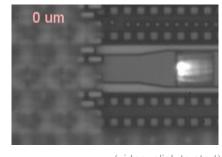


B) Beam profiles along GC



Beam profile of PIC Exit Channel in different Z-heights (WD = working distance)





(video, click to start)

UFO Probe Card: Solving the new challenges in PIC wafer testing. | JENOPTIK | Tobias Gnausch

public



UFO Probe® Card – General specifications

Specification	Current Generation	Next Generations
Device under test	Electronic and photonic integrated circuit (EPIC), Optical Transceivers for Datacom and Telecom Applications	EPIC for Transceivers, Sensors, Biosensors, LIDAR
Electrical needle technology	Cantilever, Vertical	Advanced
Optical coupling principle at DUT	Grating coupler	Grating coupler
Number of Optical Inputs/Outputs	Up to 32+	~200
Pitch OI/OO	250μm, 127μm	Typ. 250μm / 127μm, and non-standard
Layout configuration of optical OI/OO arrays	1D-Linear array with same direction of I/Os	Freely configurable (2D)
Coupling Angle	Range from 0-20°, typ. 0° and 11.6° in air	Range from 0-20°
Wavelength	1310nm and 1550nm	VIS to NIR (U-Band)
Insertion loss measurement	Repeatability: ~ 0.3 - 0.5dB	Repeatability Target: 0.1dB
RF-Measurement	Cantilever: up to 100 MHz, Vertical: GHz (digital), depending on specific needle type	Upper GHz range, depending on needle type
Number of PICs measured in parallel	1	Multi-DUT
Prober interface	Europa Card format	Europa Card format, ATE/ tester interfaces

Summary



UFO Probe®

The only commercially available solution for **High Volume PIC Testing** that runs on **standard equipment!**

Fab Proven!

Platform ready for other applications.





Supporting the digital world.

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